



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Heaton, John D.; Spady, Blaine R.  
 Assignee: Nanometrics Incorporated  
 Title: Metrology/Inspection Positioning System  
 Serial No.: 09/458,123 Filing Date:  
 Examiner: Unknown Group Art Unit: 2877  
 Docket No.: M-7677 US

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 S. Royall

San Jose, California  
 September 21, 2000

COMMISSIONER FOR PATENTS  
 WASHINGTON, D. C. 20231

INFORMATION DISCLOSURE STATEMENT  
 UNDER 37 CFR § 1.97(b)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made; or
3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on September 21, 2000.

*David Miller* 9-21-00  
 Attorney for Applicants Date of Signature

Respectfully submitted,

*David Miller*

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